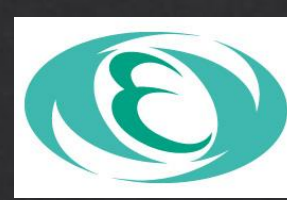
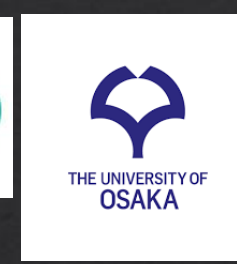




IJCLab/IN2P3



KEK



Osaka



Tsukuba HEP



2026 Joint workshop of TYL/FJPPN and FKPPN

Design and characterization of very finely pixelated AC-LGAD sensors and readout electronics

Koji Nakamura^{*1} (KEK)

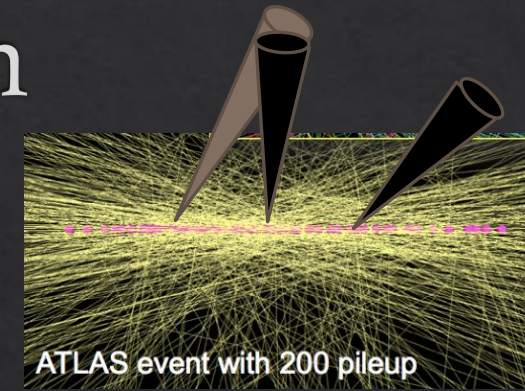
Koji Sato (Tsukuba) Tatsuya Masubuchi, Minoru Hirose (Osaka)
Ana Torrento ^{*2}, Reisaburo Tanaka, Dominique Marchand, Dmytro Hohov, Vincent Chaumat (IJCLab/IN2P3)
Christophe de la Taille (OMEGA Ecole Polytechnique-CNRS/IN2P3)

^{*1} Koji.Nakamura@cern.ch

^{*2} ana.torrento@ijclab.in2p3.fr

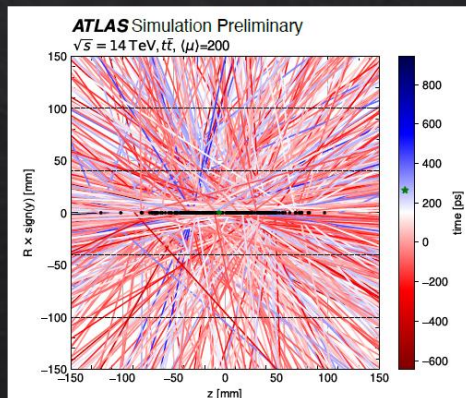
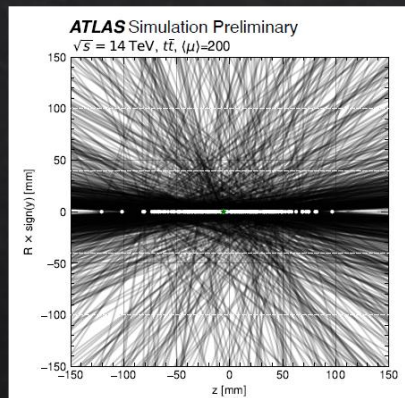


Impact for tracker with time resolution



- Collider experiment gets high energy and high intensity.
 - Future Tracking detector should have timing information for all hits!
- Tentative Requirement
 - 30ps timing resolution & $\sim o(10)\mu\text{m}$ spatial resolution
 - (hadron collider) $\sim o(10^{16})n_{\text{eq}}/\text{cm}^2$ radiation tolerance

4D tracking !



Particle identification

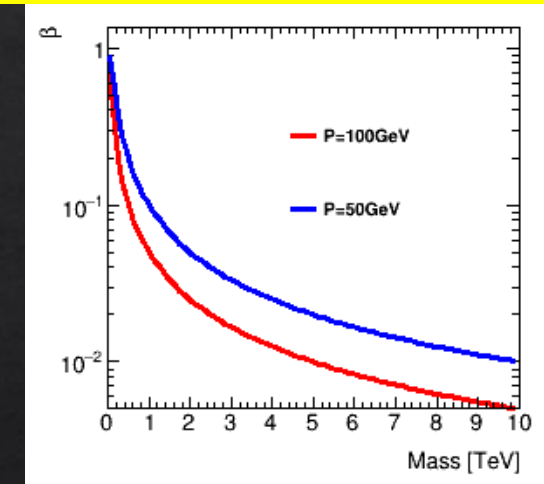
$\beta = 1$

$\beta = 0.95$



K+ π + separation

Mass spectrum for new particle



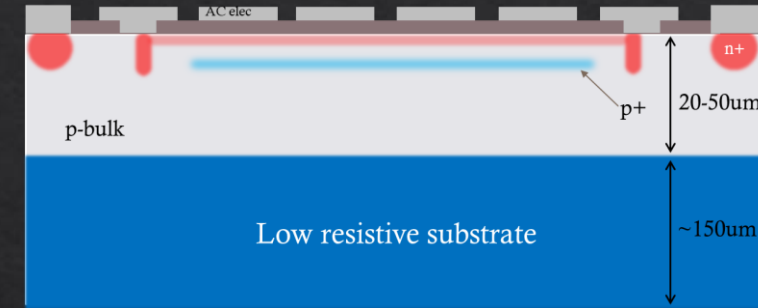
β measurement to obtain mass

e.g. Mass measurement for Long lived chargedino

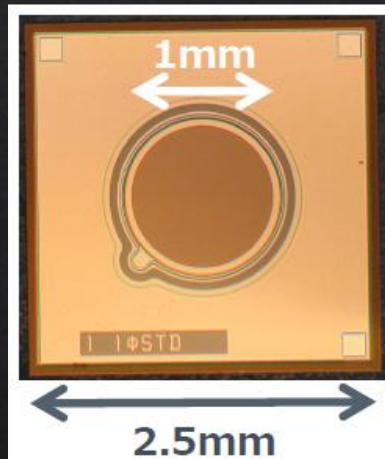
Solve pileup hits in an event

History of timing silicon detector : AC-LGAD

- ◇ **We didn't have o(10)ps timing capability MIP particle detector 10 years ago.**
- ◇ World wide LGAD detector R&D started around 2015
 - ◇ **Low Gain Avalanche Diode (LGAD) detector**
 - ◇ Hamamatsu Photonics K.K. (HPK) can produce LGAD detector in Japan!



First prototype in 2015



Recent prototype (in 2022)

AC-LGAD pixelated detector



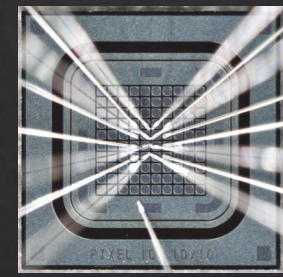
remarkable improvement

- **Spatial resolution**
- **Timing resolution**
- **Understanding Radiation hardness**

20ps timing resolution achieved

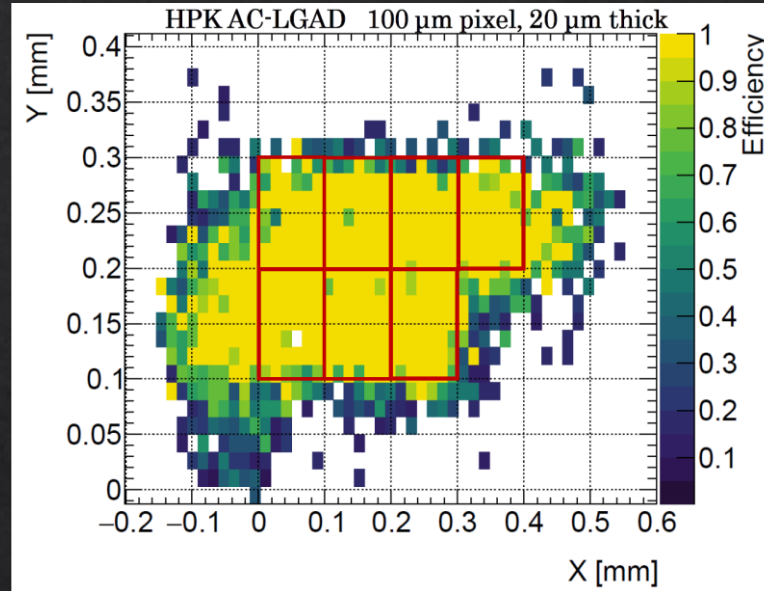
Pixel size :
100μm x 100μm
(50μm x 50μm)

Time resolution measurement

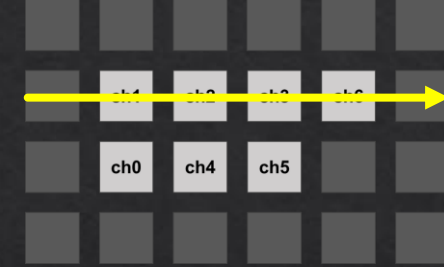


AC-LGAD with 100um x 100um pitch pixel
 Measured by ⁹⁰Sr and 3 GeV electron beam.

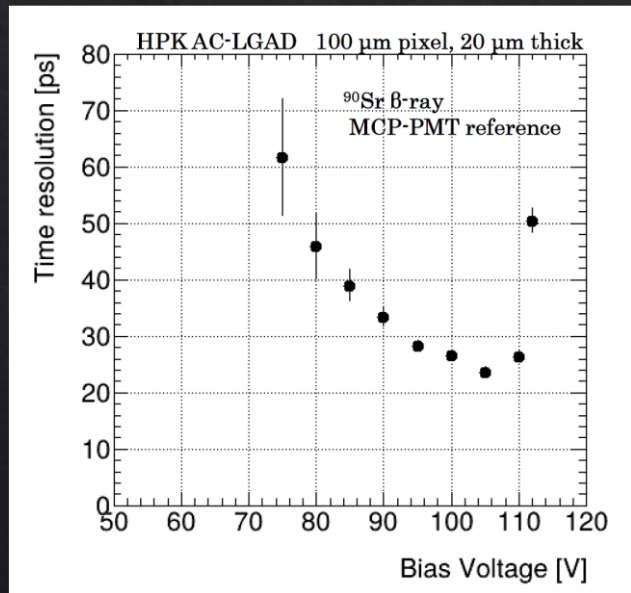
Efficiency Map



Crosstalk feature



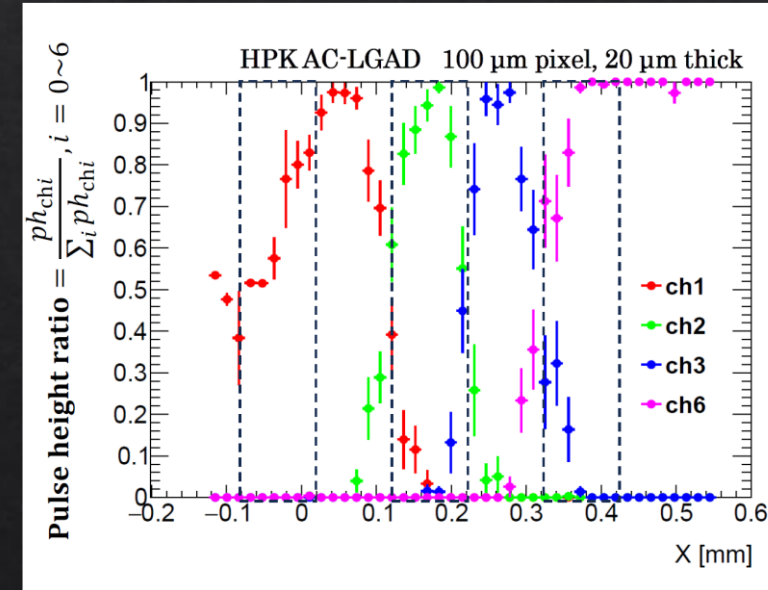
Timing resolution (⁹⁰Sr beta-ray)



$$\sigma_t = 25.3 \pm 0.1 \text{ ps}$$

Spatial resolution

	σ_{residual}	σ_{track}	σ_{detector}
X	$59.3 \pm 1.4 \text{ } \mu\text{m}$	$54.3 \pm 1.4 \text{ } \mu\text{m}$	$23.8 \pm 4.7 \text{ } \mu\text{m}$
Y	$58.2 \pm 1.3 \text{ } \mu\text{m}$	$52.6 \pm 1.2 \text{ } \mu\text{m}$	$24.9 \pm 4.0 \text{ } \mu\text{m}$



Achieved ~25ps timing resolution for 100um x 100um AC-LGAD pixel sensors

Concept of our project (RD_40)

◇ World-leading sensor development in Japan

◇ Pixelated AC-LGAD sensors developed with HPK

- ◇ Demonstrated 25 ps time resolution
- ◇ Achieved with $100\ \mu\text{m} \times 100\ \mu\text{m}$ pixel electrodes
- ◇ A unique result enabling fine segmentation and precision timing

◇ Key challenges toward detector applications

- ◇ Dedicated readout ASIC for pixelated AC-LGAD
- ◇ Optimization of radiation tolerance
- ◇ Sensor–ASIC integration and system-level performance
- ◇ Validation under realistic experimental conditions

◇ Complementary expertise from France and Japan

◇ France: OMEGA / IJCLab

- ◇ Strong ASIC development experience
- ◇ Contributions to ATLAS HGTD and ePIC Roman pots/TOF

◇ Japan

- ◇ AC-LGAD sensor design and development
- ◇ Sensor characterization and beam/radiation tests
- ◇ Close collaboration with HPK

◇ Productive collaboration framework

- ◇ Mutual use of facilities and test infrastructures
- ◇ Exchange of researchers and students
- ◇ Sharing of design ideas and technical feedback
- ◇ Focused discussions based on complementary expertise

Goal

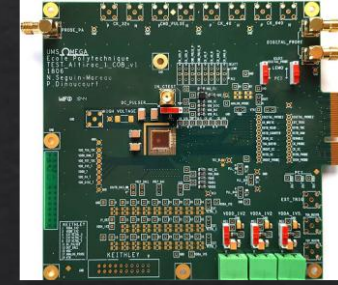
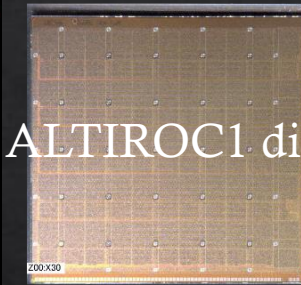
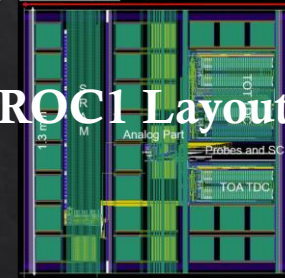
Advance pixelated AC-LGAD from a world-leading prototype toward a realistic detector technology for future experiments

Readout ASIC development

- ◇ HL-LHC upgrade : ATLAS High Granular Timing Detector (HGTD)
 - ◇ Insert 2 disks of HGTD detector between Inner Tracker and Calorimeter.
 - ◇ ALTIROC ASIC : Targeting a 50ps time resolution
- ◇ ePIC detector : Roman Pots / TOF detectors at Electron Ion Collider (EIC)
 - ◇ EICROC ASIC : Targeting 500um sq pixel with 20ps jitter (<math><2\text{mW}/\text{ch}</math>)

ALTIROC1 ASIC

One pixel layout

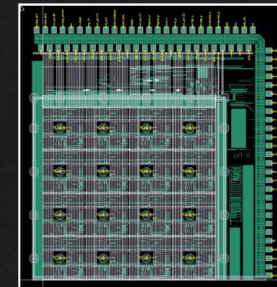


ALTIROC1 Layout

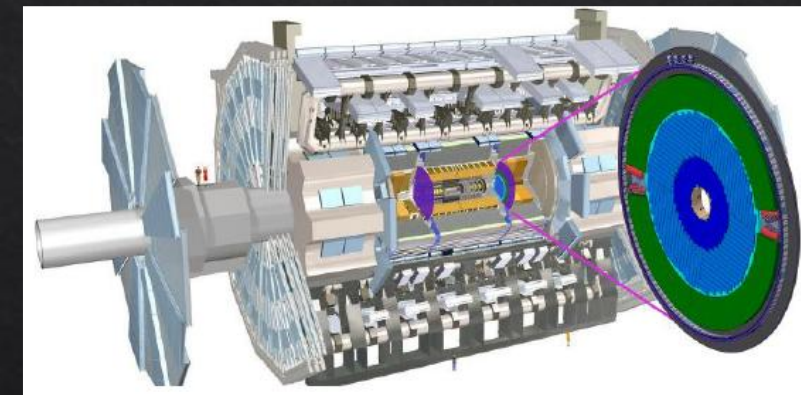
ALTIROC1 die

Plan : Application this technology to AC-LGAD pixel readout ASIC

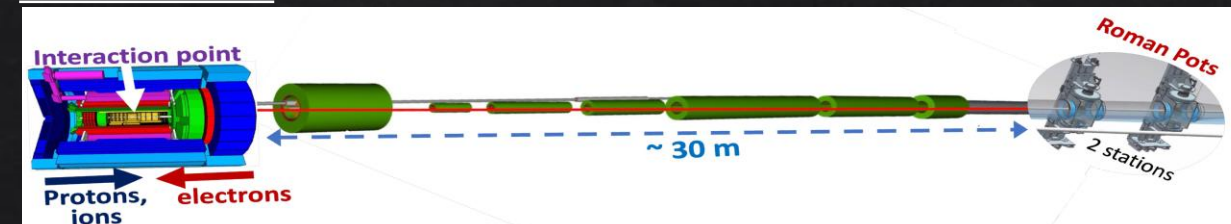
EICROC ASIC



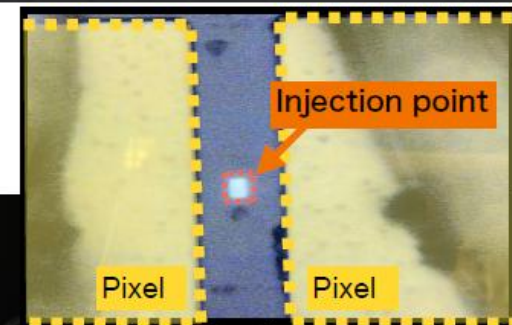
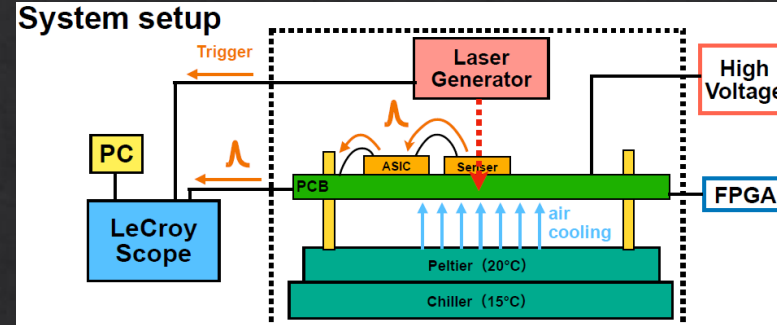
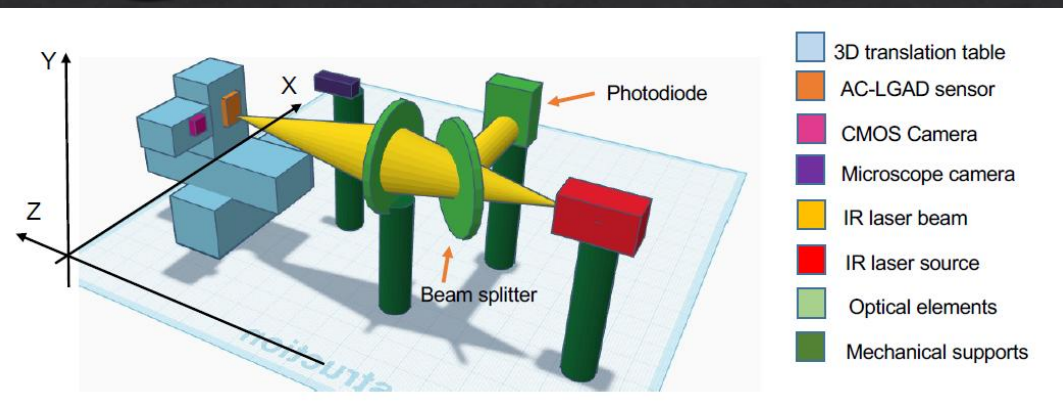
HGTD detector



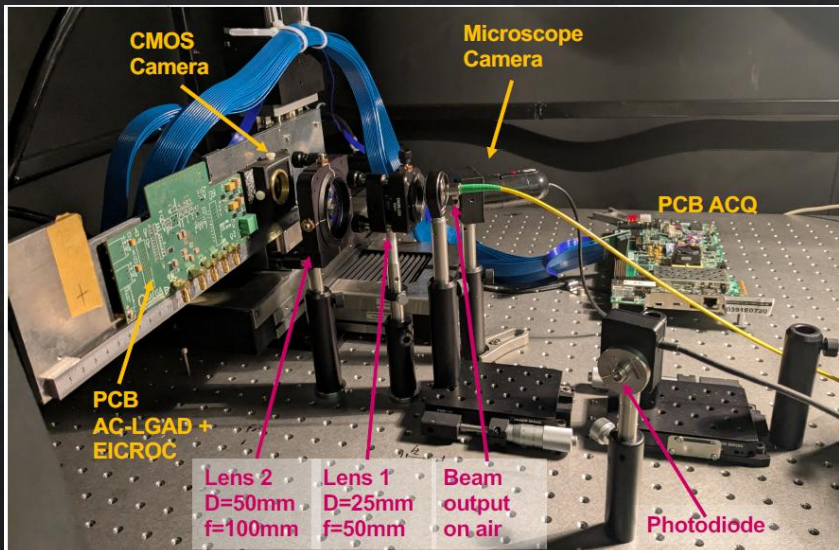
ePIC detector



Laser testbench in France and Japan



Infrared pulse laser :
Wavelength is 1064 nm.
2μm spot size

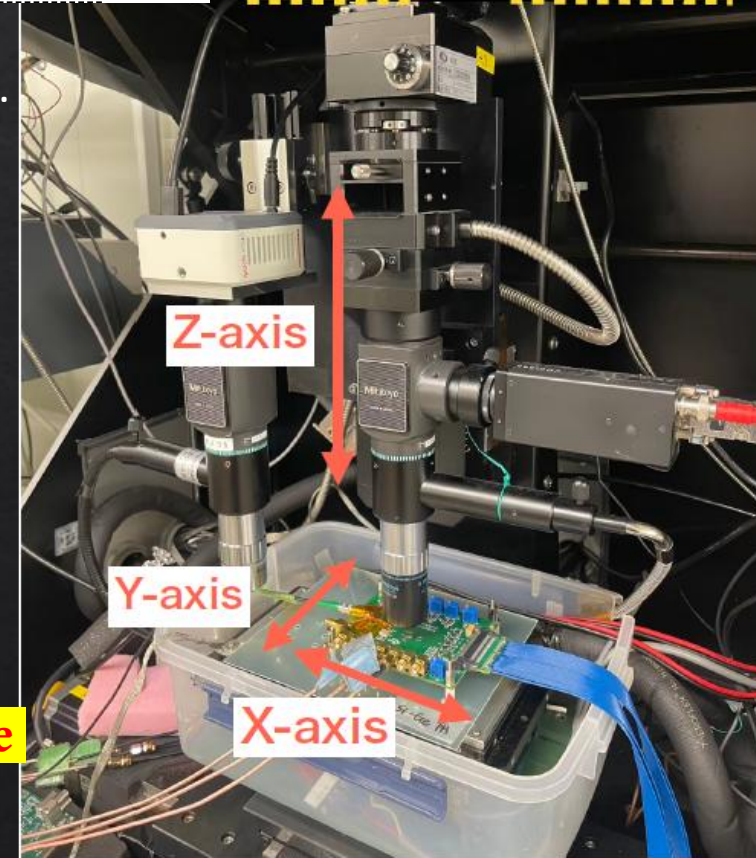


NKT Photonics Diode Laser

- 1056.4 ± 7.4 nm
- 7 nW av. Power
- 150 mW peak intensity
- 0 – 40 MHz
- 35 ps pulse width (FWHM)
- Jitter RMS = 10.8 ps
- Fiber MFD: 5.3 – 6.4 μm @ 980 nm



<8μm spot size



Complementary laser testbenches in France and Japan enable cross-checks, experience sharing, and optimized use of each setup depending on the sensor characterization needs.



AC-LGADpix Timing resolution measurement

◇ ^{90}Sr beta-ray measurement

◇ MCP-PMT as timing reference (<10ps)

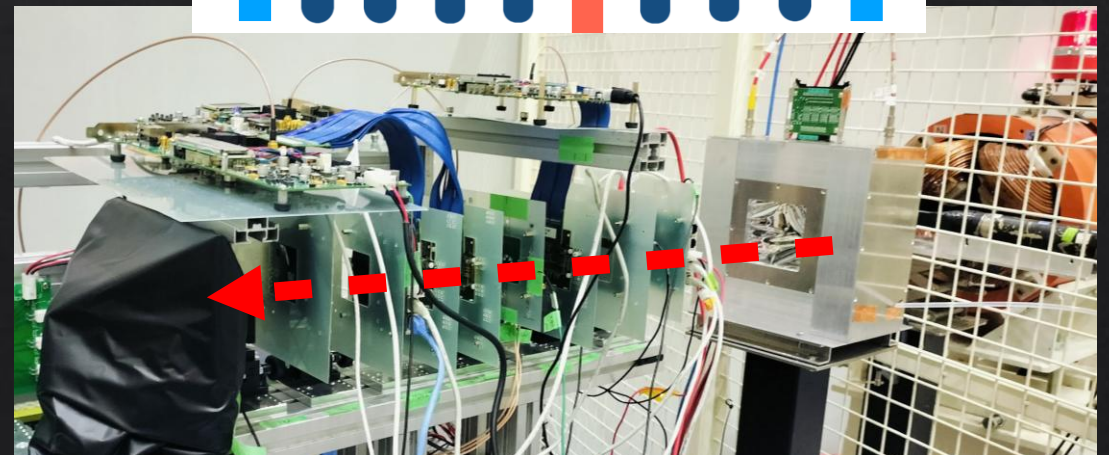
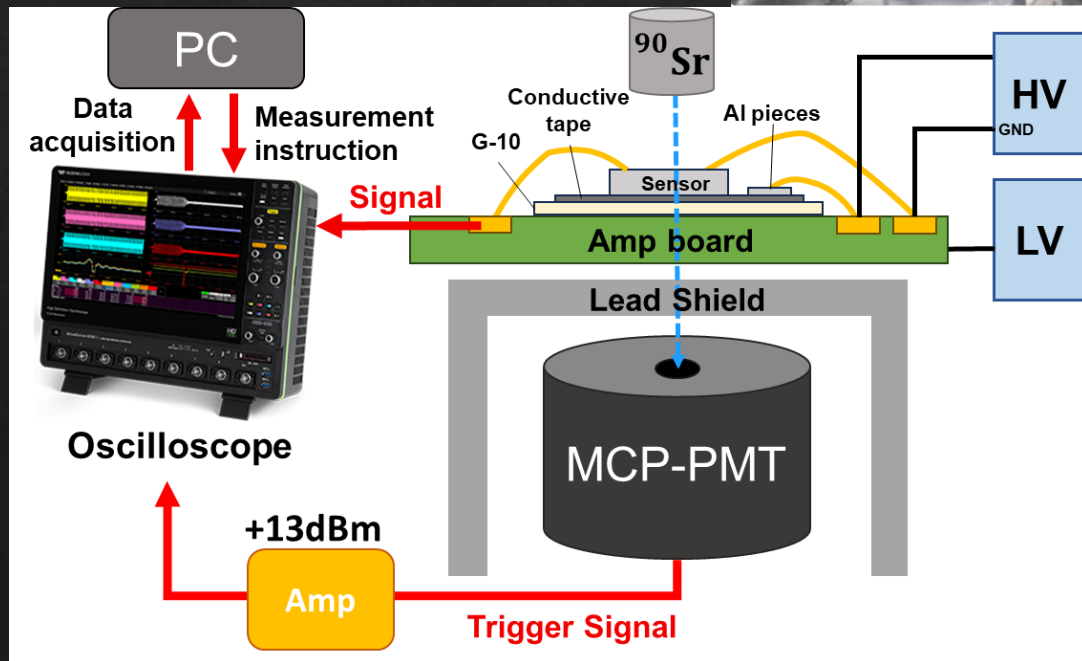
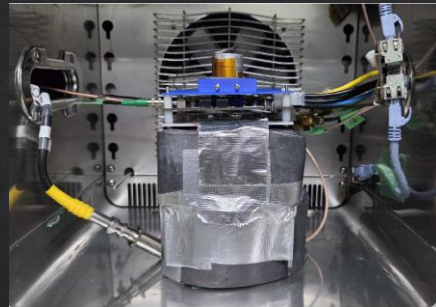
◇ Testbeam measurement at KEK AR

◇ 3-5GeV electron beam

◇ Non-negligible multiple scattering

◇ FE-I4 + MALTA based Telescope

◇ MCP-PMT as timing reference



RARiS : Irradiation Facility in Japan



- RARiS@Tohoku Univ.
 - An irradiation facility with **70MeV proton beam** ($\sim 1\mu\text{A}$ beam current).
 - 3-5 hours for $3 \times 10^{15} n_{\text{eq}}/\text{cm}^2$ irradiation with (600nA beam)
 - This allows 2-3 pixel modules with Al plate at the same time(3% E loss/module).
 - Operated at **-15°C temprature** with dry N₂ gas.
 - Scanning over full pixel range during irradiation.
 - Historically French prototype samples have been tested at CYRIC as a collaborative work.
- Facility for AC-LGAD development
 - Using this facility by sensor development very often (KEK)
 - In future, ASIC and module radiation tolerance test will be performed to develop AC-LGAD module (i.e. with sensor and ASIC)



Feb 2017
LAL's Pixel Mod.
(Active Edge)

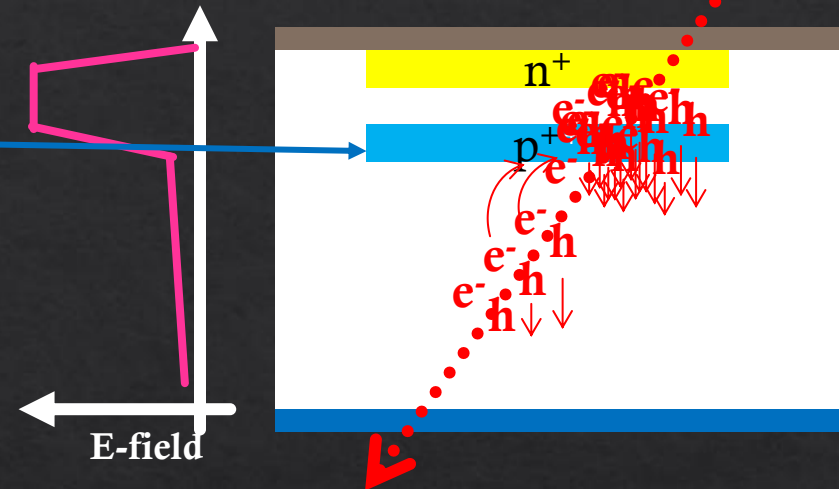


Rad hard evaluation and prototype samples

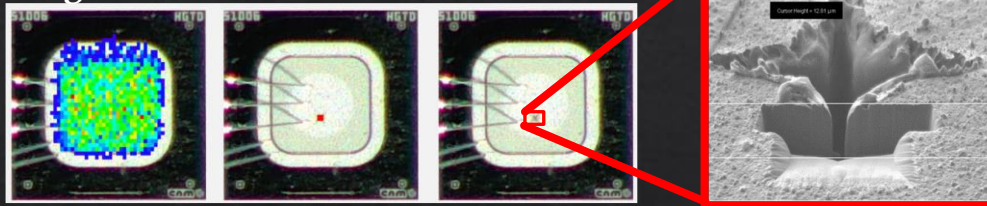
Radiation tolerance of gain layer

Electric field gets smaller by reducing p+ active impurity dope by acceptor removal. Higher Bias Voltage needed.

- ◇ Single Event Burnout expected at 12V/um ave. e-field (600V for 50um)
- ◇ Operation voltage increase (ΔV) should be smaller against fluence.



Single Event Burnout



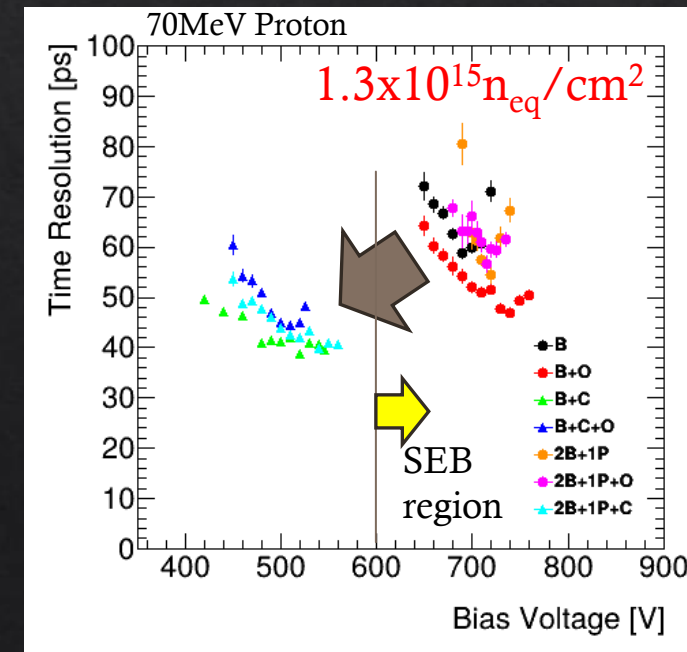
[L.A. Beresford et. al.](#)

• Prototype samples

- Oxygen enrich (B+O)
- Carbon enrich(B+C)
- Carbon and Oxygen enrich (B+O+C)
- Boron + Phosphorus (2B+1P)

• Carbon enrich samples shows improvement

- Reduction of Oxygen doesn't help.
- **First observation of improvement of radiation tolerance in HPK LGAD samples**

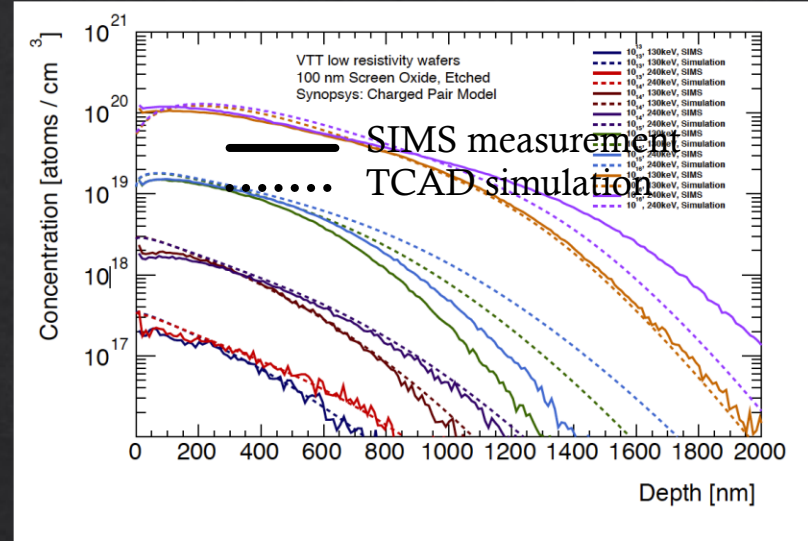




TCAD Simulation

◇ SILVACO TCAD simulation by France group

- ◇ Process simulation:
 - ◇ Simulate implantation and resulting concentrations.
 - ◇ **Can compare to SIMS result.**
- ◇ Device Simulation :
 - ◇ Simulate Electric field to understand the performance of silicon device.
 - ◇ Possible to perform simulation for charge correction of MIP signal.

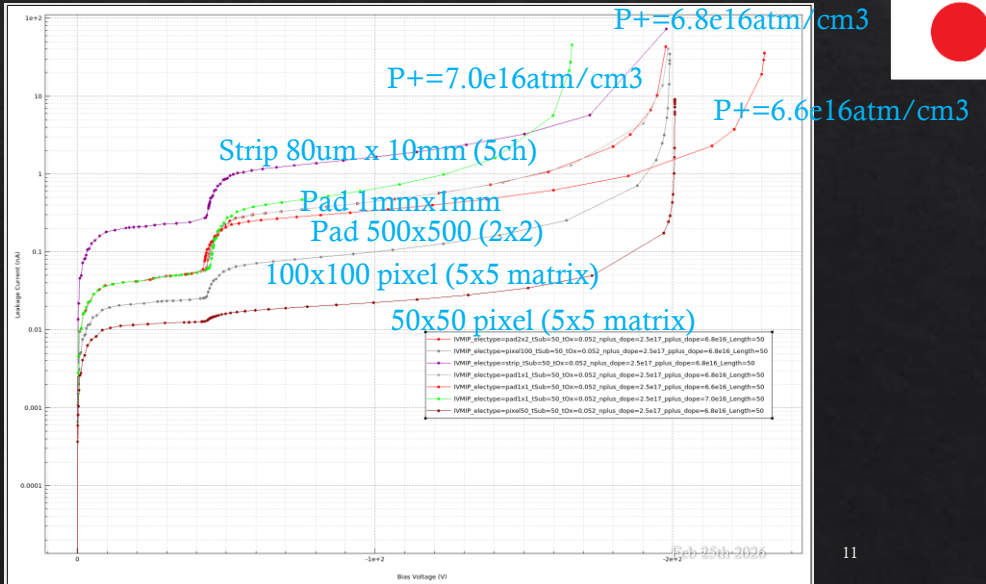
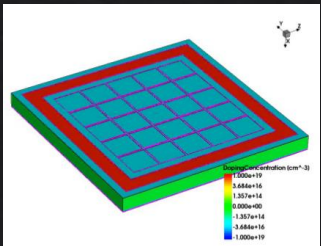


◇ AC-LGAD simulation by Japan group

- ◇ Device Simulation only :
 - ◇ Pixelated 3D device simulation
 - ◇ Avalanche break down has been demonstrated by different doping.
 - ◇ Heavily use this simulation for R&D



Exchange our experience and develop more advanced simulation framework.





MOSAIC facility at IJCLab

◆ Unique facility for detector-material R&D

◆ Multidisciplinary ion-beam platform at IJCLab / Université Paris-Saclay

◆ Ion implantation, irradiation, material modification, and surface/material analysis

4 MV Andromède

EVE Mass Spectrometer Ionic Imaging

Beam Line at 1°29
Primarily dedicated to beams from macromolecules to gold clusters

Beam line at 90°
Atomic and molecular beams from hydrogen to ions with a mass to charge ratio below 70

4 MV NEC Accelerator
ECR source & LMI source from protons to gold nanoparticles

40 kV Sidonie

Nier-Bernas source

Ion deposition
High purity isotope
Ion implantation

mosaic

Ion beams for synthesis, modification and characterization of materials, and ion-matter interactions studies

2 MV ARAMIS

SNICS negative ion source

Penning source @ HV

Nier-Bernas source

190 kV IRMA

Ion Beam Analysis

Ion irradiation
-170 to 1000°C

200 kV TEM

Ion Implantation
In situ RBS-C

JANNUS

Possible use of MOSAIC

We have started brainstorming how MOSAIC could contribute to AC-LGAD R&D.

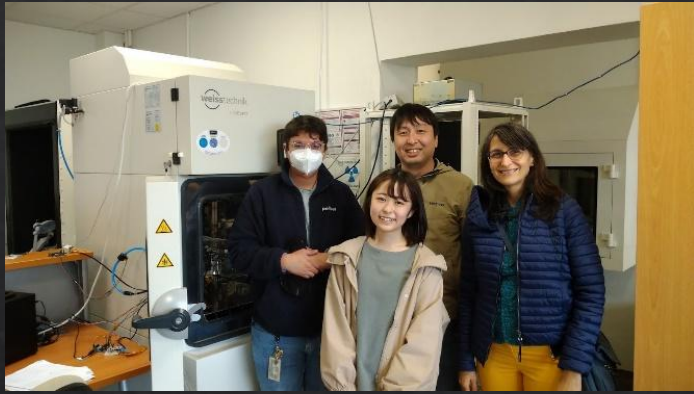
Possible directions:

- radiation-damage studies
- gain-layer degradation
- implant / process characterization
- link between material properties and sensor performance

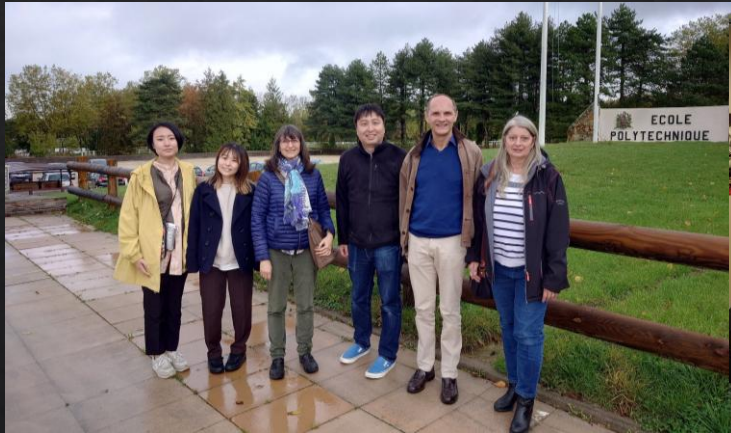
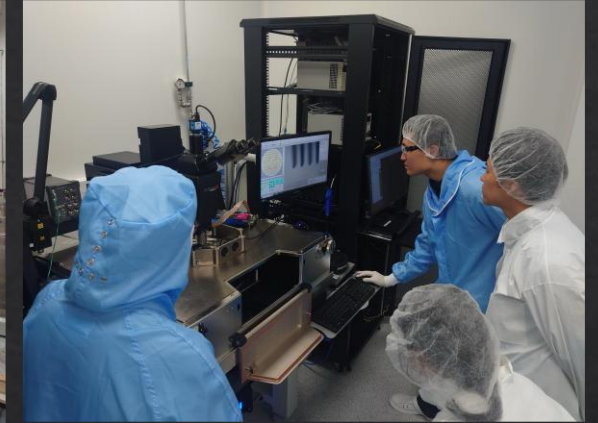
Other ideas can be explored through discussions with MOSAIC facility experts.

Exchange people and experience

Japanese team visiting IJCLab to discuss plan and to exchange experience. 2022.9



Japanese team visiting IJCLab also see MOSAIC 2024.11



Japanese team visiting IJCLab and Omega lab to learn and discuss electronics (ASIC) 2023.11



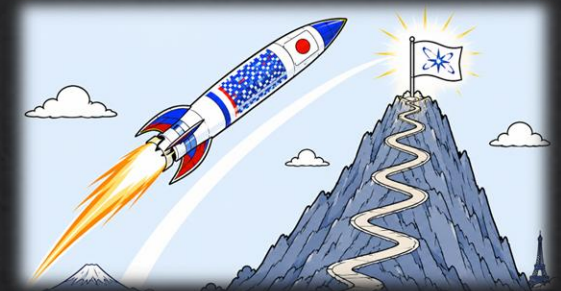
France team visiting KEK and Tateyama to learn and discuss test facilities 2025.11



Summary

◆ A complementary France–Japan R&D framework

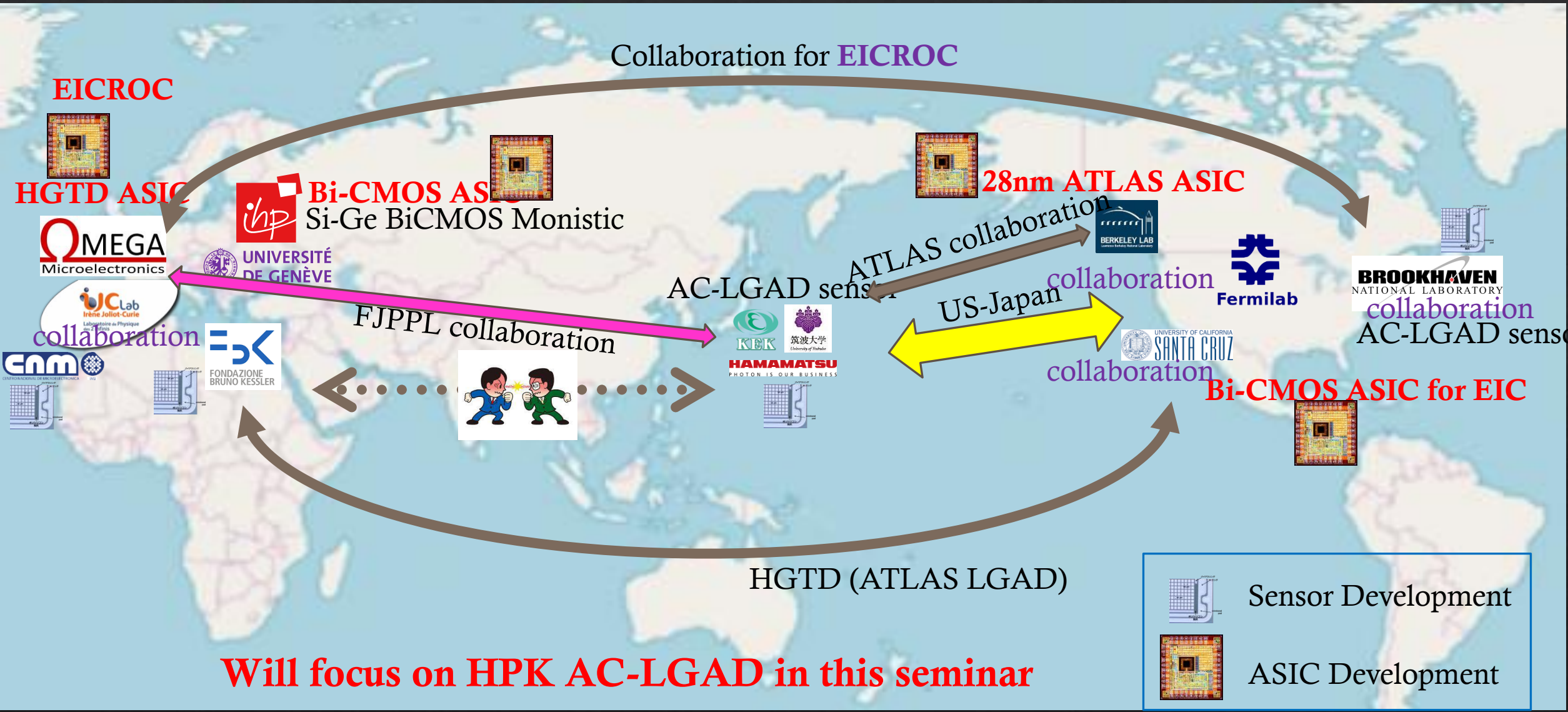
- ◆ **Pixelated AC-LGADs** are a strong candidate for future 4D tracking detectors.
- ◆ The project is driven by complementary strengths:
 - ◆ **Japan:** AC-LGAD sensor design, HPK fabrication, irradiation and testbeam experience
 - ◆ **France:** ASIC development, EICROC/ALTIROC expertise, laser and material-characterization facilities
- ◆ Joint activities connect:
 - ◆ sensor development and readout electronics
 - ◆ performance measurements and material-level studies
 - ◆ laser/source/beam tests and system integration
- ◆ Researcher exchange and shared facilities make the collaboration highly productive.



- ## ◆ Goal:
- Advance pixelated AC-LGADs from world-leading prototypes to practical detector technology through a complementary France–Japan collaboration.**

Backup

AC-LGAD collaboration



Will focus on HPK AC-LGAD in this seminar

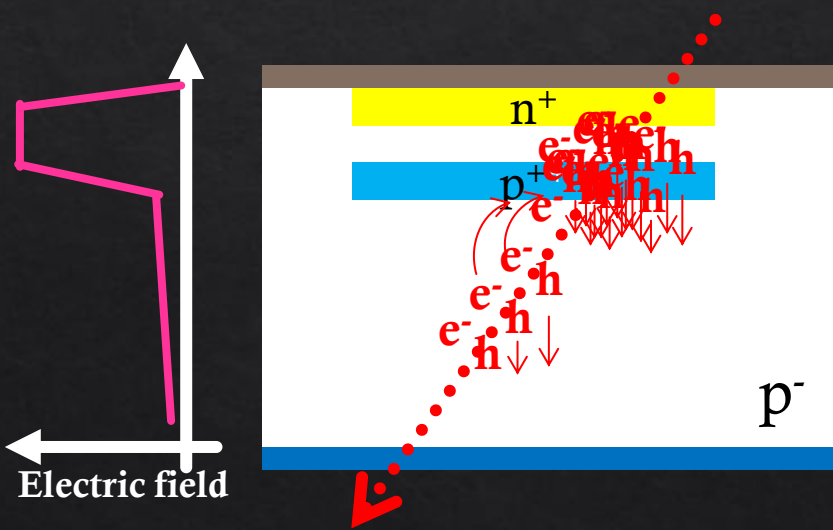
Low Gain Avalanche Diode (LGAD)

◇ Low gain Avalanche Diode (LGAD)

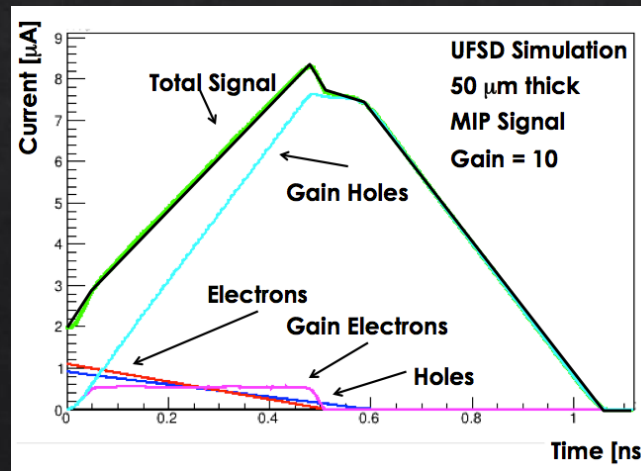
◇ General n^+ -in- p type sensor with p^+ gain layer under n^+ implant to make very high Electric Field at the surface.

→ Good timing resolution.

◇ **30ps timing resolution achieved already in 2015.**

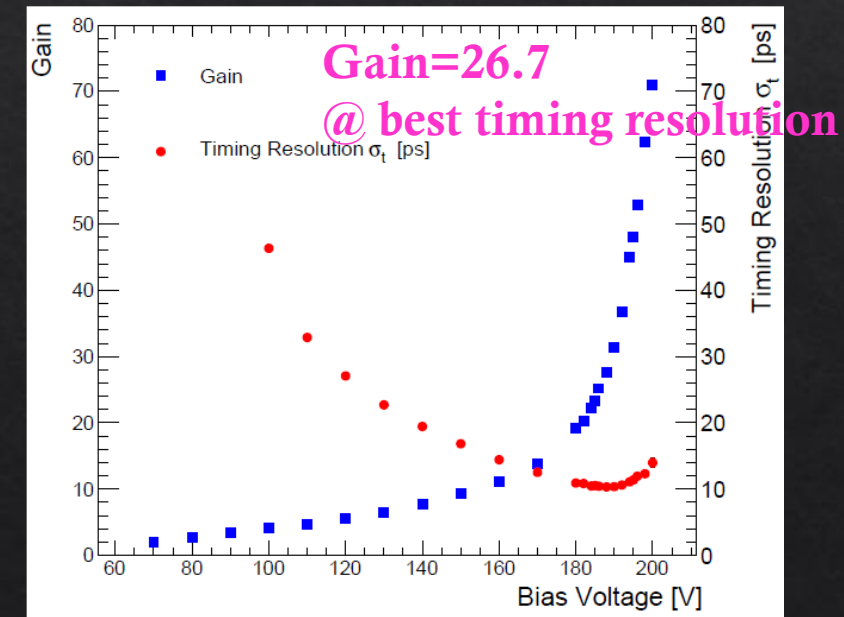


Signal drivers : Gain Holes



Cartiglia et al., NIMA [796](#), p141-148, 2015

Gain measurement (AC-LGAD):



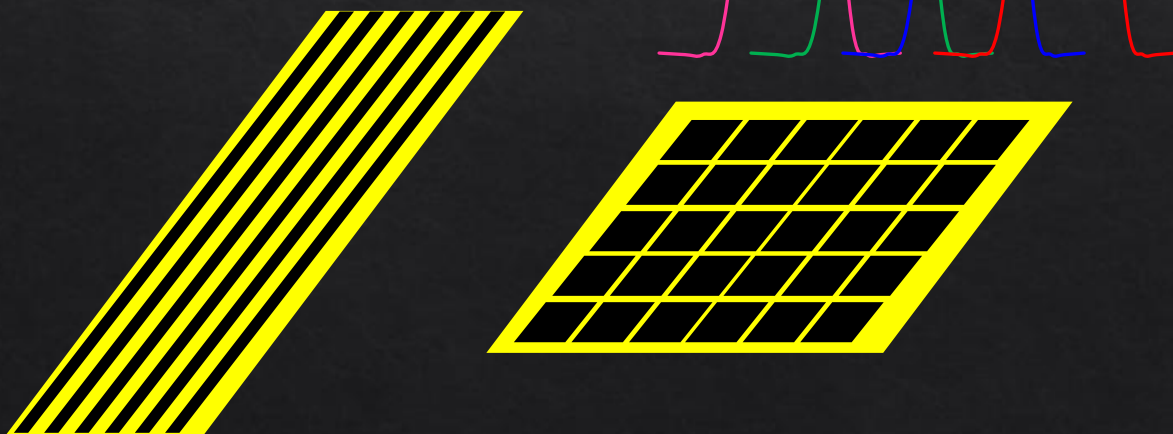
Two approaches for spatial resolution

• Charge sharing approach

- For low occupancy colliders like lepton colliders or electron-ion collider.
- Reconstruct particle position using charge sharing (charge fraction to next channels)
 - Relatively low n+ implant resistivity
- Pros. : Smaller number of channel → Save ASIC power consumption.
- Cons. : Large detector capacitance. Need high resolution ADC to get spatial resolution.

◇ Fine pitch electrode approach

- ◇ For High occupancy experiment like hadron collider.
- ◇ Reduce crosstalk (charge sharing)
 - ◇ High n+ implant resistivity
- ◇ Pros. : Smaller detector capacitance. Smaller ASIC power consumption per channel. Smaller occupancy per channel
- ◇ Cons. : # of channels get huge...



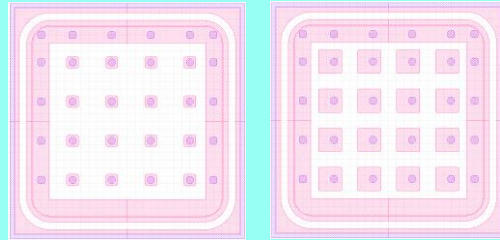
Fine pitch strip with narrow Al
(to reduce inter strip cap.)



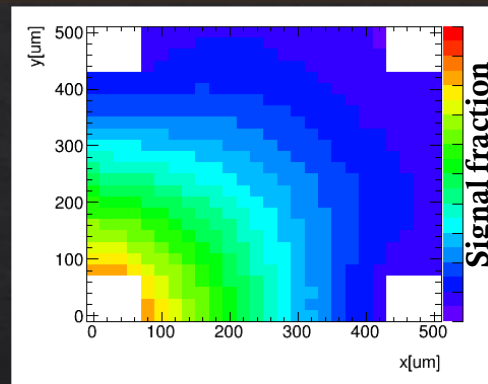
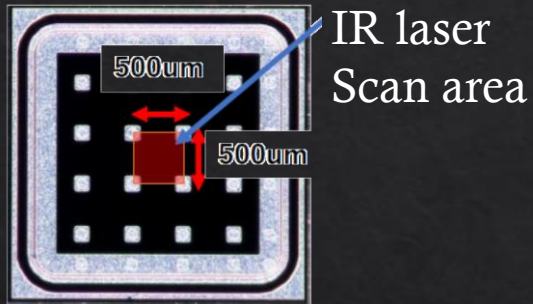
Two approaches for spatial resolution

• Charge sharing approach

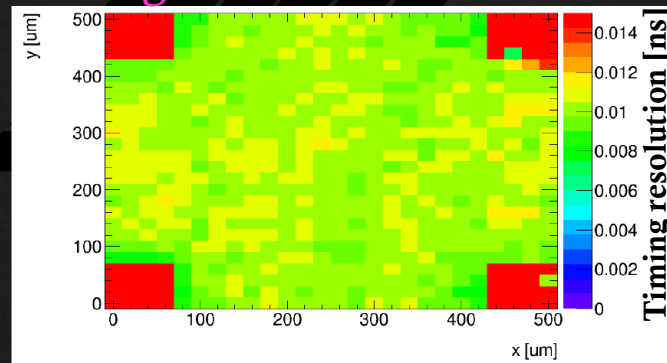
HPK EIC prototype
(500um pitch)



KEK-Tsukuba group with HPK produced
500um pitch pad/strip for future colliders (e.g. EIC)

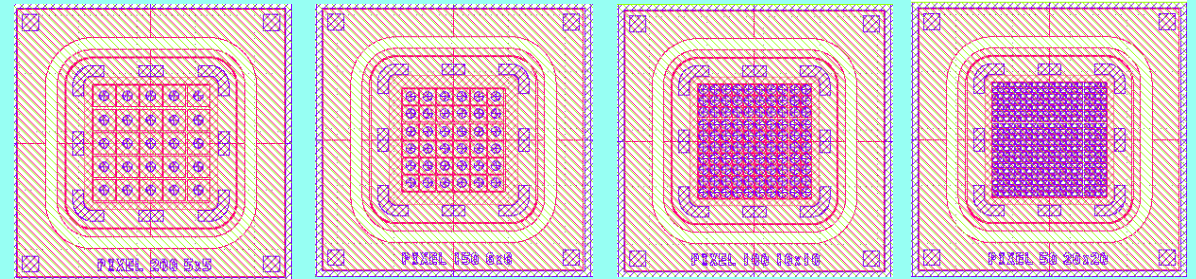


Timing resolution

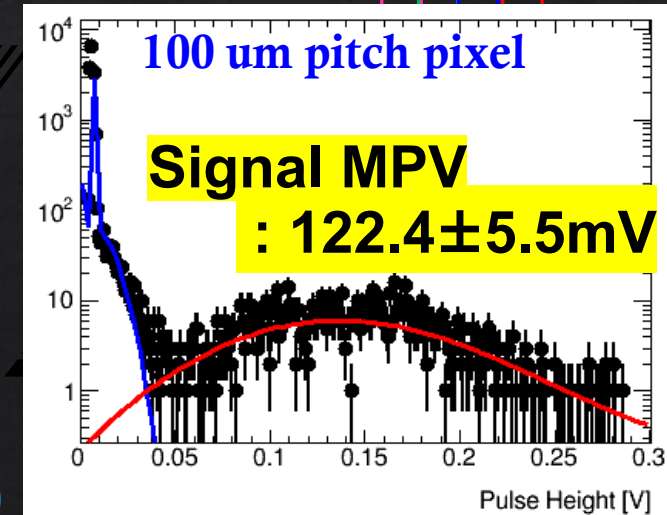
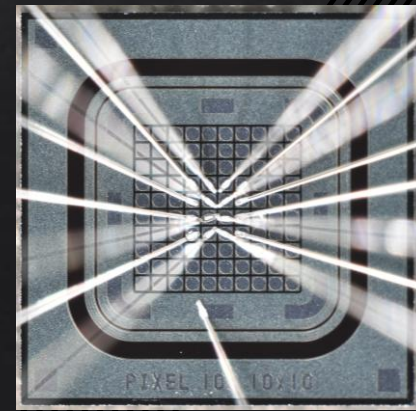
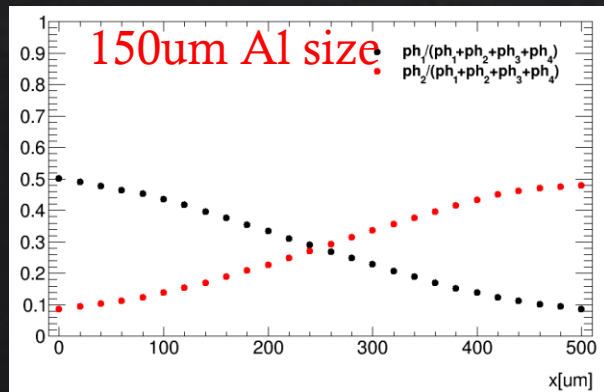


◇ Fine pitch electrode approach

200um 150um 100um 50um



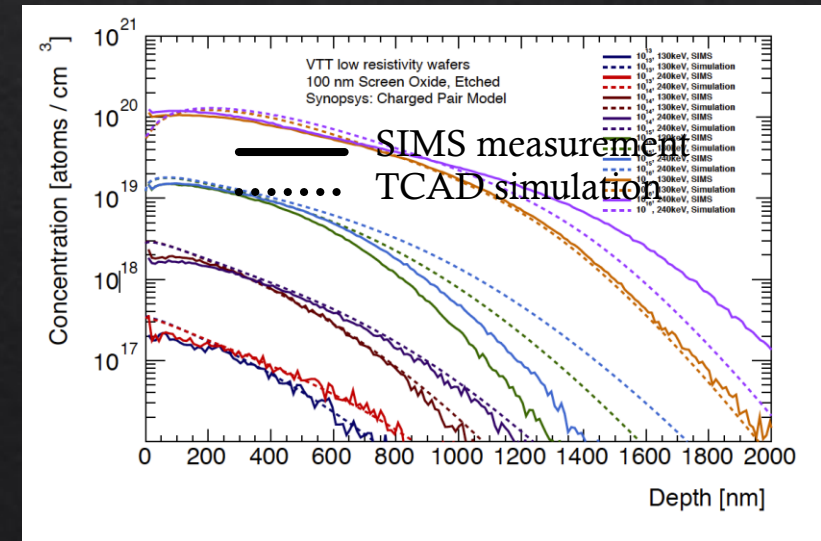
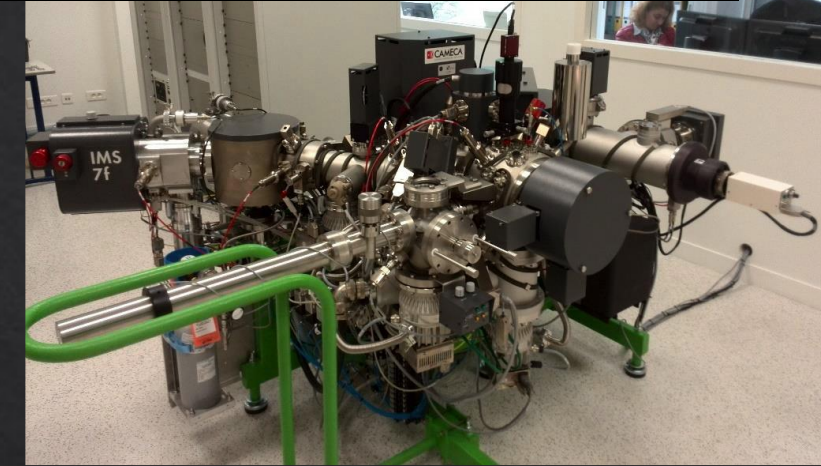
KEK-Tsukuba group with HPK successfully develop :
100um (50um) pitch Pixel detector
80um pitch Strip detector



Secondary Ion Mass Spectrometry and Simulation



SIMS system at Analyseur ionique du GEMaC
(CNRS/UVSQ, Université Paris-Saclay)



- ◇ SIMS measurement
 - ◇ Analytical technique to characterize the impurities near surface (<30um) by ionized secondary particles.
 - ◇ Good detection sensitivity for **B, P, Al, As, Ni, O, Si** etc down to **10¹³ atoms/cm³** with **1-5nm depth resolution**.
- ◇ Synopsys TCAD simulation
 - ◇ Process simulation:
 - ◇ Simulate implantation and resulting concentrations.
 - ◇ **Can compare to SIMS result.**
 - ◇ Device Simulation :
 - ◇ Simulate Electric field to understand the performance of silicon device.
 - ◇ Possible to perform simulation for charge correction of MIP signal.